



EV026159253

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner Shamim Ahmed
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 3-12-02

By: 
Mark S. Matkin
Reg. No. 32,268

03/21/2002 MNOMANN1 00000070 09360292

01 FC:126

180.00 DP

RECEIVED
MAR 22 2002
TC 1700